

ED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:

Seung-pil Chung et al.

Group Art Unit: 1763

Examiner: L. Alejandro Mulero TC 1700

Serial No.: 09/689,814

Filed: 13 October 2000

METHOD FOR REMOVING OXIDE LAYER AND SEMICONDUCTOR MANUFACTURING APPARATUS FOR REMOVING OXIDE LAYER

REQUEST FOR RECONSIDERATION

U.S. Patent and Trademark Office 2011 South Clark Place Customer Window Crystal Plaza Two, Lobby, Room 1B03 Arlington, VA 22202

Sir:

In response to the Office Action dated 25 June 2003, the period for response to which is hereby being extended by the accompanying Petition and Petition Fee to 25 October 2003, please amend the above-identified patent application as follows:

Remarks begin on page 2 of this paper.